

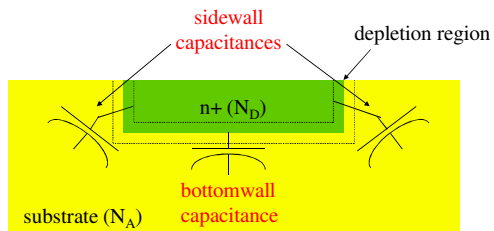
Wires

Wire parasitics

- Diffusion wire
- Poly and metal wires
- Wire-to-wire parasitics

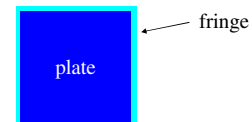
Diffusion wire capacitance

- Capacitances formed by p-n junctions:



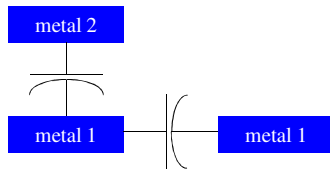
Poly/metal wire capacitance

- Two components:
 - parallel plate;
 - fringe.



Metal coupling capacitances

- Can couple to adjacent wires on same layer, wires on above/below layers:

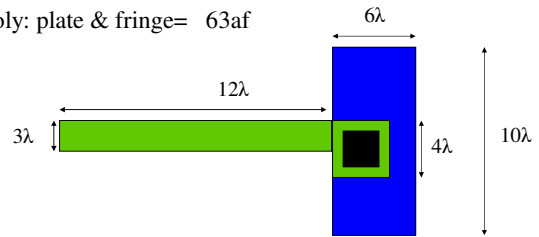


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Example: parasitic capacitance measurement

- n-diffusion: bottom wall=940 aF/um², sidewall=200 aF/um.
- metal: plate=36 aF, fringe=54 aF.
- Poly: plate & fringe= 63af



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N-diffusion layer capacitance calculation

- Bottom wall capacitance

- Area of n-diffusion layer:
 - $3 \times 12 \times \lambda^2 + 4 \times 4 \lambda^2 = 36 \lambda^2 + 16 \lambda^2 = 52 \lambda^2 = 52 (0.09 \mu\text{m})^2 = 0.4212 \mu\text{m}^2$
 - Bottom wall capacitance : $0.4212 \times 940 \text{ aF} = 0.39 \text{ fF}$

- Side wall capacitance:

- Perimeter of side wall (counter clockwise)

$$0.27 \mu\text{m} + 1.08 \mu\text{m} + 0.09 \mu\text{m} + 0.36 \mu\text{m} + 0.36 \mu\text{m} + 1.44 \mu\text{m} = 3.6 \mu\text{m}$$

- Side wall capacitance: $3.6 \times 200 \text{ af} = 0.72 \text{ fF}$

- Total n-diffusion capacitance: $0.42 + 0.72 = 1.11 \text{ fF}$

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Typical parameters for our 180 nm process.

p-type transconductance	k'_p	-30μA/V ²	poly resistivity															R_{poly}	8Ω/□	
n-type threshold voltage	V_{tn}	0.5V	metal 1-substrate plate capacitance	$C_{metal1,plate}$														36aF/μm ²		
p-type threshold voltage	V_{tp}	-0.5V	metal 1-substrate fringe capacitance	$C_{metal1,fringe}$														54aF/μm		
n-diffusion bottomwall capacitance	$C_{ndiffbot}$	940aF/μm ²	metal 2-substrate capacitance	$C_{metal2,plate}$														36aF/μm ²		
n-diffusion sidewall capacitance	$C_{ndiffside}$	200aF/μm	metal 2-substrate fringe capacitance	$C_{metal2,fringe}$														51aF/μm		
p-diffusion bottomwall capacitance	$C_{pdiffbot}$	1000aF/μm ²	metal 3-substrate capacitance	$C_{metal3,plate}$														37aF/μm ²		
p-diffusion sidewall capacitance	$C_{pdiffside}$	200aF/μm	metal 3-substrate fringe capacitance	$C_{metal3,fringe}$														54aF/μm		
n-type source/drain resistivity	R_{ndiff}	7Ω/□	metal 1 resistivity	R_{metal1}														0.08Ω/□		
p-type source/drain resistivity	R_{pdiff}	7Ω/□	metal 2 resistivity	R_{metal2}														0.08Ω/□		
poly-substrate plate capacitance	$C_{polyplate}$	63aF/μm ²	metal 3 resistivity	R_{metal3}														0.03Ω/□		
poly-substrate fringe capacitance	$C_{polyfringe}$	63aF/μm	metal current limit	$I_{m,max}$														1mA/μm		

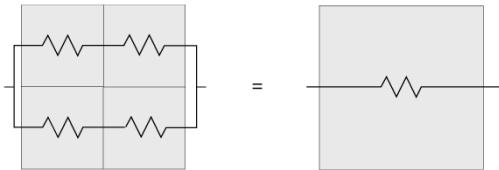
- What will be metal wire capacitance?

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Wire resistance

- Resistance of any size square is constant:



Skin effect

- At low frequencies, most of copper conductor's cross section carries current.
- As frequency increases, current moves to skin of conductor.
 - Back EMF induces counter-current in body of conductor.
- Skin effect most important at gigahertz frequencies.

Skin effect, cont'd

- Isolated conductor:
- Conductor and ground:



Low frequency



High frequency



Low frequency



High frequency

Skin depth

- Skin depth is depth at which conductor's current is reduced to $1/3 = 37\%$ of surface value:
 - $\delta = 1/\sqrt{\pi f \mu \sigma}$
 - f = signal frequency
 - μ = magnetic permeability
 - σ = wire conductivity

Effect on resistance

- Low frequency resistance of wire:
 - $R_{dc} = 1 / \sigma w t$
- High frequency resistance with skin effect:
 - $R_{hf} = 1 / 2 \sigma \delta (w + t)$
- Resistance per unit length:
 - $R_{ac} = \text{sqrt}(R_{dc}^2 + \kappa R_{hf}^2)$
- Typically $\kappa = 1.2$.